



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :  
Jyun IWASHITA et al. : **Confirmation No. 6956**  
Serial No. 10/808,425 : **Attn: BOX MISSING PARTS**  
Filed March 25, 2004 : **Attorney Docket No.2004\_0468A**

NEGATIVE RESIST MATERIAL AND  
METHOD FOR FORMING RESIST PATTERN

**CLAIM OF PRIORITY UNDER 35 USC 119**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450


Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 2003-084981, filed March 26, 2003, as acknowledged in the Declaration of this application.

A certified copy of said Japanese Patent Application is submitted herewith.

Respectfully submitted,

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